

Amendments to the Specification:

Please replace the paragraph beginning at page 6, line 10, with the following
AMENDED paragraph:

Figure 2 is a sectional view showing the apparatus for etching a glass substrate according to the present invention. As shown in the figure, the etching apparatus according to the present invention comprises an etching bath 211 filled with etchant 221, a Teflon cassette 217 in the interior of the etching bath 211, said cassette 217 supporting a substrate 219 including a color filter substrate and a TFT substrate and an ultrasonic oscillator 223 that is generating ultrasonic vibration and is attached to the exterior of the etching bath 211, and which removes impurity by ultrasonic oscillation. In another aspect of the present invention, the ultrasonic oscillator 223 may be located within the interior of the etching bath 211.